### **INTERNATIONAL STANDARD**



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# Microbeam analysis — Methods of specimen preparation for analysis of general powders using WDS and EDS

lyse i. Analyse par microfaisceaux — Méthodes de préparation des



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### Foreword

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This document was prepared by Technical Committee ISO/TC 202, Microbeam analysis.

Any feedback or questions on this document should be directed to the user's national standards body. A complete listing of these bodies can be found at <u>www.iso.org/members.html</u>.

### Introduction

Although there are many applications of electron probe microanalysis (EPMA) and scanning electron microscopy (SEM) for powder analysis, there are some difficulties, especially in the case of individual particle analysis, as follows:

- (a) the prevention of agglomeration of particles during preparation of the specimen;
- (b) the fixation of specimens, especially when there is a small amount of tiny particles, either for surface analysis or cross-section analysis;
- (c) the cross-section preparation in the case of small particles with core-shell structures;
- (d) the protection of particle surfaces from damage by electron beam irradiation in cases where the surfaces of particles are sensitive;
- (e) the counteraction of charging of the specimen under electron radiation to prevent the powder from scattering or dispersing due to electrical repulsion;
- (f) the interpretation of qualitative and/or quantitative analysis results when the X-ray generation volume is larger than that of the particles.

Even in the case of elemental compositional analysis of a powder, the specimen preparation can affect the results of analysis, because the roughness and/or void space within a particle aggregate or agglomerate can impact X-ray intensity.

To cope with these difficulties, the standardization of specimen preparation for particle analysis is very important.

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# Microbeam analysis — Methods of specimen preparation for analysis of general powders using WDS and EDS

### 1 Scope

This document specifies specimen preparation methods for the analysis of particles in powders using energy-dispersive spectrometers (EDS) or wavelength-dispersive spectrometers (WDS) installed on an EPMA or SEM. The preparation methods for powder particle analysis are classified by the analytical purpose and the particle size.

This document applies to inorganic particles larger than 100 nm and smaller than 100 µm in diameter.

It applies only to analysis of "general" powders, which means that it excludes procedures for special applications such as forensic or trace analysis.

### 2 Normative references

There are no normative references in this document.

### 3 Terms and definitions

No terms and definitions are listed in this document.

ISO and IEC maintain terminological databases for use in standardization at the following addresses:

- ISO Online browsing platform: available at <a href="https://www.iso.org/obp">https://www.iso.org/obp</a>
- IEC Electropedia: available at http://www.electropedia.org/

### 4 Abbreviated terms

- EDS energy-dispersive X-ray spectroscopy/spectrometry
- EPMA electron probe microanalysis/electron probe microanalyzer
- SEM scanning electron microscopy/scanning electron microscope
- WDS wavelength-dispersive X-ray spectroscopy/spectrometry/spectrometer

## 5 Analytical purposes and methods of specimen preparation for particle analysis<sup>[1]</sup>

### 5.1 Methods of specimen preparation for particle analysis

The following methods of specimen preparation are widely used for particle analysis (see Figure 1). The specific procedure is indicated in 5.2.

This list is not comprehensive and does not preclude the use of other specimen preparation methods for particle analysis that can be more appropriate in some cases.